

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Priority Application Serial No. ..... 10/229,887  
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Inventor ..... Eugene Marsh et al.  
Assignee ..... Micron Technology, Inc.  
Priority Group Art Unit ..... 2822  
Priority Examiner ..... Jamie Lynn Brophy  
Attorney's Docket No. ..... MI22-2461  
Title ..... Atomic Layer Deposition Methods

**PRELIMINARY AMENDMENT**

To: Mail Stop Patent Application  
Commissioner for Patents  
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Alexandria, VA 22313-1450

**VIA EXPRESS MAIL**

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Please enter the following amendments prior to examining the above-identified application.

**AMENDMENTS**